

## EAST Search History

## EAST Search History (Prior Art)

| Ref # | Hits  | Search Query  | DBs   | Default Operator | Plurals | Time Stamp          |
|-------|-------|---|---|------------------|---------|---------------------|
| L1    | 4     | "2002037506"  | US-PGPUB;<br>USPAT;<br>USOCR; FPRS;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | ADJ              | ON      | 2009/08/12<br>16:25 |
| L2    | 1     | 2002-426843.NRAN.   | DERWENT   | ADJ              | ON      | 2009/08/12<br>16:25 |
| L3    | 4120  | (anodi\$6) with<br>(silicon or Si) with<br>(substrate or support<br>or etch)                      | US-PGPUB;<br>USPAT;<br>USOCR; FPRS;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | ADJ              | ON      | 2009/08/12<br>16:29 |
| L4    | 8859  | anode with (porous<br>or pore or porosity)<br>with (film or coat or<br>coating or layer)          | US-PGPUB;<br>USPAT;<br>USOCR; FPRS;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | ADJ              | ON      | 2009/08/12<br>16:29 |
| L5    | 8257  | cathode with (porous<br>or pore or porosity)<br>with (film or coat or<br>coating or layer)        | US-PGPUB;<br>USPAT;<br>USOCR; FPRS;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | ADJ              | ON      | 2009/08/12<br>16:29 |
| L6    | 15813 | electrolyte with<br>(porous or pore or<br>porosity) with (film<br>or coat or coating or<br>layer) | US-PGPUB;<br>USPAT;<br>USOCR; FPRS;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | ADJ              | ON      | 2009/08/12<br>16:29 |
| L7    | 2064  | L4 with L5 with L6  | US-PGPUB;<br>USPAT;<br>USOCR; FPRS;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | ADJ              | ON      | 2009/08/12<br>16:29 |

|     |      |  |   |     |    |                     |
|-----|------|--|---|-----|----|---------------------|
| L8  | 3    | L7 with 3  | US-PGPUB;<br>USPAT;<br>USOCR; FPRS;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | ADJ | ON | 2009/08/12<br>16:29 |
| L9  | 5    | L7 same 3  | US-PGPUB;<br>USPAT;<br>USOCR; FPRS;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | ADJ | ON | 2009/08/12<br>16:30 |
| L10 | 2    | 9 not 8  | US-PGPUB;<br>USPAT;<br>USOCR; FPRS;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | ADJ | ON | 2009/08/12<br>16:30 |
| L11 | 17   | L7 and 3   | US-PGPUB;<br>USPAT;<br>USOCR; FPRS;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | ADJ | ON | 2009/08/12<br>16:31 |
| L12 | 7    | 11 and fuel cell   | US-PGPUB;<br>USPAT;<br>USOCR; FPRS;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | ADJ | ON | 2009/08/12<br>16:32 |
| L13 | 7    | 12 not 9   | US-PGPUB;<br>USPAT;<br>USOCR; FPRS;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | ADJ | ON | 2009/08/12<br>16:32 |
| S14 | 8859 | anode with (porous<br>or pore or porosity)<br>with (film or coat or<br>coating or layer)   | US-PGPUB;<br>USPAT;<br>USOCR; FPRS;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | ADJ | ON | 2009/08/12<br>13:30 |
| S15 | 8257 | cathode with (porous<br>or pore or porosity)<br>with (film or coat or<br>coating or layer) | US-PGPUB;<br>USPAT;<br>USOCR; FPRS;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | ADJ | ON | 2009/08/12<br>13:30 |

|     |       |   |   |     |    |                     |
|-----|-------|---|---|-----|----|---------------------|
| S16 | 15813 | electrolyte with (porous or pore or porosity) with (film or coat or coating or layer) | US-PGPUB;<br>USPAT;<br>USOCR; FPRS;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | ADJ | ON | 2009/08/12<br>13:30 |
| S17 | 2064  | S14 with S15 with S16   | US-PGPUB;<br>USPAT;<br>USOCR; FPRS;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | ADJ | ON | 2009/08/12<br>13:30 |
| S18 | 2     | S17 with (etch or etch\$3) with (silicon or Si) with (substrate or support or etch)   | US-PGPUB;<br>USPAT;<br>USOCR; FPRS;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | ADJ | ON | 2009/08/12<br>13:31 |
| S19 | 47    | S17 and (etch or etch\$3) with (silicon or Si) with (substrate or support or etch)    | US-PGPUB;<br>USPAT;<br>USOCR; FPRS;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | ADJ | ON | 2009/08/12<br>13:31 |
| S20 | 51    | S17 and (etch or etch\$3) same (silicon or Si) with (substrate or support or etch)    | US-PGPUB;<br>USPAT;<br>USOCR; FPRS;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | ADJ | ON | 2009/08/12<br>13:31 |
| S21 | 34    | S17 and (etch or etch\$3) with (silicon or Si) with (substrate or support or base)    | US-PGPUB;<br>USPAT;<br>USOCR; FPRS;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | ADJ | ON | 2009/08/12<br>13:31 |
| S22 | 2     | S17 with (etch or etch\$3) with (silicon or Si) with (substrate or support or base)   | US-PGPUB;<br>USPAT;<br>USOCR; FPRS;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | ADJ | ON | 2009/08/12<br>13:31 |

**EAST Search History (I nterference)**

&lt; This search history is empty &gt;

**8/ 12/ 2009 4:56:19 PM****C:\ Documents and Settings\ RAlejandro\ My Documents\ EAST\ Workspaces\ default2.wsp**